

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re:	Detlef Michelsson	Confirmation No:	5672
Serial No:	10/772,510	Art Unit:	2624
Filed:	February 5, 2004	Examiner:	Fujita, Katrina R.
For:	Method and Apparatus for Examining Semiconductor Wafers in a Context of DIE/SAW Design		
Customer No.:	29127		
Attorney Docket No.	21295.74 (H5742US)		

### **AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION**

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Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In the above-identified patent application and in response to the pending final Office Action, mailed October 30, 2007 (Paper No. 20071025), a Request for Continued Examination is hereby made. Accordingly, entry of the following amendments and reconsideration are requested in view of the following remarks.

Amendments to the Claims are reflected in the listing of claims in the Amendments to the Claims section.

Reconsideration is requested in view of the remarks set forth in Remarks/Arguments section.